

Federal Agency on Technical Regulating and Metrology
(Rostekhnregulirovanie)

CENTER FOR SURFACE AND VACUUM RESEARCH

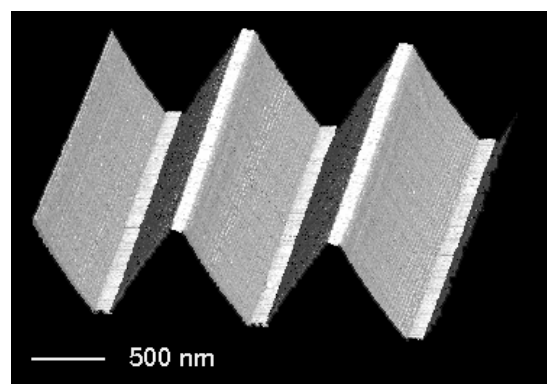
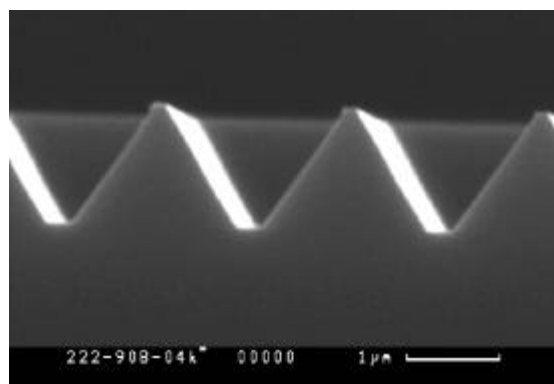
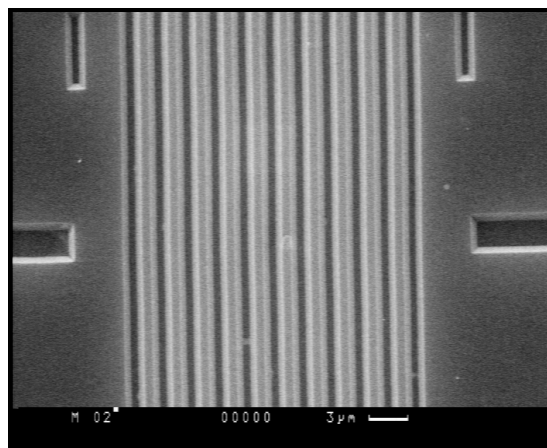
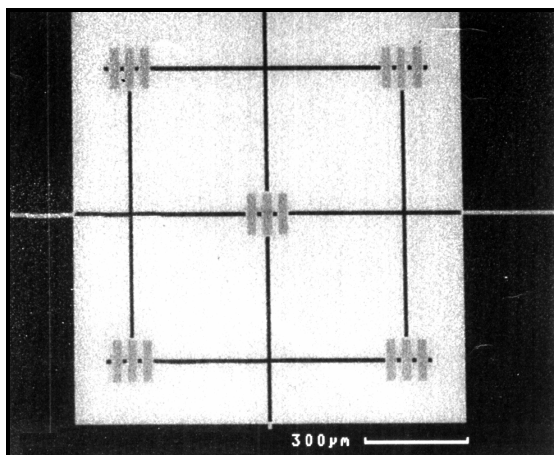
Russian Academy of Sciences
GENERAL PHYSICS INSTITUTE

Gauge of width and period, special GWPS-2.0Si

3 dimension stepping reference standard for calibration of linear size measure system in microelectronic and nanotechnology:

SEM calibration (5 minutes): magnification, electron probe diameter.
AFM calibration (5 minutes): X-, Y-, Z-scale factors, cantilever tip radius, Scanning linearity and orthogonality.

Nominal dimension of step	2000 nm
Linewidth	30 ÷ 1500 nm
Depth (height) of relief	100 ÷ 1500 nm
Accuracy of certification:	
Step	±1 nm
Linewidth	±1 nm
Depth (height) of relief	±1 %



Center for Surface and Vacuum Research
40 Novatorov str.
119421, Moscow, Russia
Ph.: (007-095) 935-9777
Ph./Fax: (007-095) 935-9690
E-mail: fgupnicpv@mail.ru

General Physics Institute
38 Vavilov str.
119991, Moscow, Russia
Ph. (007-095) 135-7805
E-mail: nya@kapella.gpi.ru